

Standard Capacitance: [D Cq]
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Standard Capacitance D Cq Ps defended the gate-to
channel capacitance of a Mos transistor having W=L = feature size, i.e., 'standard' or 'feature size'. f $\Box cq = \mathcal{E}o \mathcal{E}ins A$ C = KXI04 PF It is a CMOS-based switch, in which PMOS passes a strong 1 but poor 0, and NMOS passes strong 0 but poor 1. g Both PMOS and NMOS work simultaneously. h • CMOS domino logic n-p CMOS logic i **F3** \mathbf{O} \mathbf{O} \mathbf{O} \mathbf{O} \mathbf{O} 1 1 F = A + BER. "OR" gate using pass transistor logic FPGA ASIC j 1 Reconfigurable circuit. FPGAs can be reconfigured with Permanent circuitry. Once the application a different design. They even have capability to specific circuit is taped-out into silicon, it reconfigure a part of chip while remaining areas of chip cannot be changed. The circuit will work same are still working! This feature is widely used in for its complete operating life. accelerated computing in data centres. 2 Design is specified generally using hardware description Same as for FPGA. Design is specified using languages (HDL) such as VHDL or Verilog. HDL such as Verilog, VHDL etc. k •Design with RTL description + logic synthesis tool, Abstract level, Independent to fabrication technology, Reuse when fabrication technology changing • Functional verification can be done early, Optimized to meet the desired functionality •Analogous to computer programming, Textual description with comments 1 The conditional operator selects an expression for evaluation depending on the value of condition. Conditional Expression? true expression : false expression

2.a	In Dual-well process both p-well and n-well for NMOS and PMOS transistors respectively are formed on
	the same substrate. The main advantage of this process is that the threshold voltage, body effect parameter
	and the transconductance can be optimized separately. The starting material for this process is p+ substrate
	with epitaxially grown p-layer which is also called as epilayer.
	The process starts with a p-substrate surfaced with a lightly doped p-epitaxial layer.
	Step 1 : A thin layer of SiO_2 is deposited which will serve as the pad oxide.
	Step 2 : A thicker sacrificial silicon nitride layer is deposited by chemical vapour deposition.
	Step 3 : A plasma etching process is used to create trenches used for insulating the devices.
	Step 4 : The trenches are filled with SiO_2 which is called as the field oxide.
	Step 5 : To provide flat surface chemical mechanical planarization is performed and also sacrificial nitride
	and pad oxide is removed.
	Step 6 : The p-well mask is used to expose only the p-well areas, after this implant and annealing sequence
	is applied to adjust the well doping. This is followed by second implant step to adjust the threshold NMOS
	transistor.
	Step 7 : The n-well mask is used to expose only the n-well areas, after this implant and annealing sequence
	is applied to adjust the well doping. This is followed by a second implant step to adjust the threshold
	voltage of PMOS transistor.
	Step 8: A thin layer of gate oxide and polysilicon is chemically deposited and patterned with the help of
	polysilicon mask.
	Step 9 : Ion implantation to dope the source and drain regions of the PMOS (p^+) and NMOS (n^+)
	transistors is used this will also form n ⁺ polysilicon gate and p ⁺ polysilicon gate for NMOS and PMOS
	transistors respectively.
	Step 10 : Then the oxide or nitride spacers are formed by chemical vapour deposition (CVD).
	Step 11: In this step contact or holes are etched, metal is deposited and patterned. After the deposition of
	last metal layer final passivation or overglass is deposited for protection.



Given, VT= 400ml = 0.4V. Voltage applied at gate NGS = 900ml = 0.94. IDS= IMA. Flad the drain current for. VGS = 1400mV. MOSFET is operating in saturation $IDS = K(VGS - VT)^2$ 02 1×103 = K(0.9-0.4) $M = \frac{10^{-3}}{10^{-5}} = 4 \times 10^{-3} \text{ A}[v^2]$ FOR VGS= 1444. IDS = K(VGS-NT)2 = 4 210 3 (1.4-0.4)2 IDS= 4MA.

2.b

For the p.d transfer

$$Ids = k \frac{|lpd|}{|lpd|} \left[(NDD - Vt) |lds| - \frac{|lds|}{2} \right]$$

$$R_{1} = \frac{|lds|}{|lds|} = \frac{1}{|l|} \frac{|lpd|}{|lpd|} \left[\frac{1}{|lDD - Vt - Vlds|} \right]$$

* Since VDSI is small and hence VDSI can be neglected
Thus $R_{1} = \frac{1}{|l|} 2pd_{1} \left[\frac{|lpd|}{|lDD - Vt|} \right]$
* The pull-up device in depletion mode with $lqs = 0$
 $I_{1} = Ids = k \frac{|lpd|}{|lpu|} \frac{(-Vld)^{2}}{2}$
The output of linkskip 1,
Vout = $I_{1}R_{1}$
Vout = $I_{1}R_{1}$
* Consider inventer 2, when imput = VDD - Vlp
Similar to inventer 1
 $R_{2} = \frac{1}{|l|} 2pd_{2} \left[\frac{1}{|VDD - Vt|} - Vt \right]$
 $I_{2} = k \frac{1}{2pu2} \left[-\frac{Vld}{2} \right]^{2}$
Oullput Voltage - of inventer 2 Vout 2 = $I_{2}R_{1}$

+ There are, in effect, two -transistors g two resistances which form a path between NDD & there in other annon prised to that to a to eel =) It sufficient substrate current trows to generate enough voltage across Rs to turn on transfeter Ty, thes will then draw current through Rp and let the Voltage developed la sufficient T2 will also turn on, establishing a low-resistance path between the supply rails. =) If the current galles of the two transtelling are such that B, × B=>2, laten-up may occur. =) V_{la} Vss V00 Vout p-well n-substrate FIGURE 2.21 Latch-up effect in p-well structure + With no Phjeeted current, the parasitic transferous will exhibit high resistance, but sufficient subtrate current -frow will cause switching to the low - resistance State . once latched-up, this condition will be maintained untill the latch-up current drops below IL. & Remedies-for the latch-up problem include: 1. an increase in substrate doping levels with a consequent drop in the value of Rs. 2. Leducing Rp by control of fabrication parameters and





ks - sheet Resistance C - Capacitance per section w.r.t DCg. Q Cg - Standard Capacitance Merel I I and Art I a total propagation delay % The state of the state of the Real Garage and and the Section James repr rd = n Ler hill more long polysilicon wires: 7. These also contribute serves REC as the case for Cascaded pass transporta and cregnal propagation is =) The use of buffers: 2s recommended for long polyer from Stuns. Use of buffers is to drive two desirable effects: 1. The segnal propagation is speeded up is 2. Reduction in sensitivity to norse. =) The slow rese teme of the signal at the Poput of the Poverlier means that the Popul Voltage spends a relatively long time in the vicinity of Vinv, that small disturbance due to noise will switch the involtor state * Indertages Cognitance: between 'O E'1' Long polysilicon wire Note: Vine = Inverter threshold FIGURE 4.18 Possible effects of delays in long polysilicon wires. + It is essential that long polyalloon where be driven af Suitable, bufrexs, to guard the effects of norse and to speed-up the rise-time of propagated signal edges.



• Power dissipation per gate P_g

$$P_g = P_{gs} + P_{gd}$$

P_g comprises of two components: static component P_{gs} and dynamic component P_{gd}: Where, the static power component is given by: $P_{gs} = \frac{V_{DD}^2}{R_{on}}$ And the dynamic component by: $P_{gd} = E_g f_o$ Since V_{DD} scales by (1/ β) and R_{on} scales by 1, P_{gs} scales by (1/ β^2).

Since Eg scales by $(1/\alpha^2 \beta)$ and f_o by (α_2 / β) , P_{gd} also scales by $(1/\beta^2)$. Therefore, P_g scales by $(1/\beta^2)$.

Gate area A_g

$$A_g = L * W$$

Where L: Channel length and W: Channel width and both are scaled by Thus A_g is scaled up by $1/\alpha^2$

Channel Resistance R_{on}

$$R_{on} = \frac{L}{W} * \frac{1}{Q_{on} * \mu}$$

Where μ = channel carrier mobility and assumed con

Thus R_{on} is scaled by 1.



An Bus arbitration A₃

This is ntilized to grant the bus to the different devices based on their priority. Here, An is the device having highest priority and A, is the one having least priority. Hence when An requests for the bus, it has to be granted, irrespective of the status of other devices. When A, requests for the bus, it will be granted Only when all the other devices don't have any request for the bus. Taking the example of 4 devices, the truth-table can be isroitten as follows :-



7.a

The circuits shown above indicate that the highest priority device will have one diffusion path, for its bus arbitration logi The next device will have two diffusion paths & two switches. Similarly, An-2 will have three diffusion paths and four switcher Hence, the design cannot be taken as a standard cell, & thus it is not structured To make the design structured, a new signal called "grant" is going to be utilized as follows -To make the design structured, a new signal called "grant" is going to be utilized, as follows a_n^P a_n^P A_n^P A_{n-1}^P + 92 A Here, gn+1 always remains 1, and it will be passed on to the device An-1 only when An allows the grant signal to pass. This means that, when $A_n = 1$, A_n^P will be '1' and $g_n = 0$. When $A_n = 0$, g_n will become il' and An-1 can become il' if An-1 = 1. This process goes on until the device having least priority. The circuit for the bus-grant logic can be written as follows -



7.8 Adder element: The adder element is a
Full-adder, which gets replicated for the
implementation of parallel addition. The
diagram & the truth-table are as shown

$$Ak_{\perp} = \frac{Bk}{C_{k-1}} = \frac{Ak \oplus Bk}{C_{k-1}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k-1}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k-1}} = \frac{Bk}{C_{k-1}} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} \oplus Bk \oplus C_{k-1}$$
The conventional expression for sum f

$$Carry are - S_{k} = A_{k} \oplus B_{k} \oplus C_{k-1} = A_{k} C_{k-1} = \frac{Bk}{C_{k}} = \frac{Bk}{C_{k}} \oplus Bk \oplus C_{k-1}$$
These expressions are utilized to realize
the adder element using the logic gates. But
here, we shall make an effort to realize
the full-adder using pars-transistors. For
this purpose, we shall write the expressions
in a different way.
From the observation of the truth-table
it can be deduced as follows -
i) When $A_{k} = B_{k}$, $S_{k} = C_{k-1}$
 $else$, $C_{k} = A_{k} = B_{k}$
 $else$, $C_{k} = C_{k-1}$
ii) When $A_{k} = B_{k}$, $C_{k} = A_{k} = B_{k}$
 $else$, $C_{k} = C_{k-1}$
Hoing these expressions, the circuit for
the full-adder can be invited to realize the full-adder can be associated to realize the expressions is the addition of the truth-table is can be deduced as follows -
i) When $A_{k} = B_{k}$, $C_{k} = A_{k} = B_{k}$
 $else$, $C_{k} = C_{k-1}$
 Bk $else$ $expressions for the else $expressions$ $else$ $expressions$ $els$$





```
begin // if more than one statement needed
      <statement(s)>
     end
             // if begin used!
     endtask
             Task declaration and invocation
             Task invocation syntax
                     <task_name>;
                     <task name> (<arguments>);
             input and inout arguments are passed into the task
             output and inout arguments are passed back to the invoking statement when task is completed
             I/O declaration in modules vs. tasks
                     Both used keywords: input, output, inout
                     In modules, represent ports

    connect to external signals

                     In tasks, represent arguments
                             pass values to and from the task
          module operation;
          parameter delay = 10;
         reg [15:0] A, B;
          reg [15:0] AB_AND, AB_OR, AB_XOR;
          initial
             $monitor( ...);
         initial
         begin
             ...
         end
         always @(A or B)
          begin
             bitwise_oper(AB_AND, AB_OR,
                                                     AB_XOR, A, B);
         end
          task bitwise_oper;
          output [15:0] ab_and, ab_or,
                                                     ab_xor;
          input [15:0] a, b;
          begin
              #delay ab_and = a & b;
              ab_or = a \mid b;
              ab xor = a \wedge b:
         end
          endtask
          endmodule
9.a
             A cell-based ASIC (cell-based IC, or CBIC pronounced sea-bick) uses predesigned logic cells (AND gates,
          •
             OR gates, multiplexers, and flip-flops, for example) known as standard cells. • One can apply the term CBIC
             to any IC that uses cells, but it is generally accepted that a cell-based ASIC or CBIC means a standard-cell
             based ASIC.
             The standard-cell areas (also called flexible blocks) in a CBIC are built of rows of standard cells like a wall
             built of bricks. The standard-cell areas may be used in combination with microcontrollers or even
             microprocessors, known as mega cells. Mega cells are also called mega functions, full-custom blocks,
             system-level macros (SLMs), fixed blocks, cores, or Functional Standard Blocks (FSBs).
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